

PATENT APPLICATION

				Page 1 of 1 🖸
FORM PTO-1449	ATTY. DKT NO.	1-99	SER. NO.	I.d. T
	APPLICANT	MATSUI	•	976
	FILING DATE	Nov. 13, 2000	GROUP	13
		· · · · · · · · · · · · · · · · · · ·	•	# 0 6

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
13	5,750,434	. May 12, 1998	Urushidani et al.	_	_
7/3	5,800,577	Sept. 1, 1998	Kido		
		·			

FOREIGN PATENT DOCUMENTS

TRANSLATION

						IKANSLA	HON	_
DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO	
7-80770 (cited in spec. p. 4)	3/95	JAPAN		_			(
56-23746 (cited in spec. p. 5)	6/81	JAPAN	_		-		_	
7-288243	10/95	JAPAN			_	X AB	STRACT	1,00
8-22503	3/96	JAPAN			_	ХΑ	STRAC	├ U
664540	12/94	EPO			_	-	1	
-	_							
	7-80770 (cited in spec. p. 4) 56-23746 (cited in spec. p. 5) 7-288243 8-22503 664540	NUMBER 3/95 7-80770 (cited in spec. p. 4) 56-23746 (cited in spec. p. 5) 7-288243 10/95 8-22503 3/96 664540 12/94	NUMBER DATE COUNTRY 7-80770 (cited in spec. p. 4) 3/95 JAPAN 56-23746 (cited in spec. p. 5) 6/81 JAPAN 7-288243 10/95 JAPAN 8-22503 3/96 JAPAN 664540 12/94 EPO	NUMBER DATE COUNTRY NAME 7-80770 (cited in spec. p. 4) 3/95 JAPAN — 56-23746 (cited in spec. p. 5) 6/81 JAPAN — 7-288243 10/95 JAPAN — 8-22503 3/96 JAPAN — 664540 12/94 EPO —	NUMBER DATE COUNTRY NAME CLASS 7-80770 (cited in spec. p. 4) 3/95 JAPAN — — 56-23746 (cited in spec. p. 5) 6/81 JAPAN — — 7-288243 10/95 JAPAN — — 8-22503 3/96 JAPAN — — 664540 12/94 EPO — —	NUMBER DATE COUNTRY NAME CLASS 7-80770 (cited in spec. p. 4) 3/95 JAPAN — — 56-23746 (cited in spec. p. 5) 6/81 JAPAN — — — 7-288243 10/95 JAPAN — — — 8-22503 3/96 JAPAN — — — 664540 12/94 EPO — — —	DOCUMENT NUMBER DATE COUNTRY NAME CLASS SUB CLASS YES 7-80770 (cited in spec. p. 4) 3/95 JAPAN — — — — 56-23746 (cited in spec. p. 5) 6/81 JAPAN — — — — 7-288243 10/95 JAPAN — — X AB 8-22503 3/96 JAPAN — — X AB 664540 12/94 EPO — — — —	NUMBER DATE COUNTRY NAME CLASS CLASS YES NO 7-80770 (cited in spec. p. 4) 3/95 JAPAN — </td

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

1)	Kikuchi et al., "Mechanochemical Polishing of Silicon Carbide Single Crystal with				
18	Chromium(III) Oxide Abrasive", <u>J. Am. Ceram. Soc.</u> , 75 [1], pp. 189-94 (1992)				
	(Note: This article is discussed at page 4 of the specification).				
)					
EXAMINER	DATE CONSIDERED 10/31/01				
J FOO	July 1				

Rev. 10/94 (Form 3.05)